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(B)

**RESPONSE UNDER 37 C.F.R. § 1.116**  
**EXPEDITED PROCEDURE REQUESTED**  
**EXAMINING GROUP 2818**  
**PATENT**  
Attorney Docket No. 04329.3238

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:	)	
	)	
Gaku MINAMIHABA et al.	)	Group Art Unit: 2818
	)	
Application No. 10/771,060	)	Examiner: Goodwin, David J.
	)	
Filed: February 4, 2004	)	Confirmation No.: 2231
	)	
For: POLISHING PAD AND METHOD OF	)	<b>Mail Stop AF</b>
MANUFACTURING	)	
SEMICONDUCTOR DEVICES	)	

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT AFTER FINAL**

In reply to the Final Office Action mailed August 25, 2006, the period for response to which extends through November 27, 2006 (November 25<sup>th</sup> being a Saturday), and pursuant to 37 C.F.R. § 1.116, Applicants propose that this application be amended as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks/Arguments** follow the amendment section of this paper.